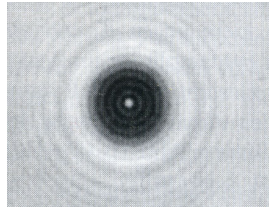


## Diffraction at a Circular Aperture: Babinet Principle

Circular Disc



Circular Aperture



The diffraction pattern at an aperture and a complementary disc are equal in intensity if the undiffracted light is subtracted.

## Generalized Babinet Principle

for an infinitely thin, ideally conducting film

The following relations hold for the diffracted fields (near- and far-fields) of an aperture A and its complementary disc K:

$$E_A \rightarrow -H_K$$

$$H_A \rightarrow E_K$$

## Near-fields at a circular nano-aperture: approximate solution of Bouwkamp

**Oblate-spheroidal coordinates (with radius a of the aperture):**

$$z = auv, \quad x = a\sqrt{(1-u^2)(1+v^2)} \cos \varphi, \quad y = a\sqrt{(1-u^2)(1+v^2)} \sin \varphi,$$

where  $0 \leq u \leq 1$ ,  $-\infty \leq v \leq \infty$ ,  $0 \leq \varphi \leq 2\pi$ . The surfaces  $v = 0$  and  $u = 0$  correspond to the aperture and the screen, respectively.

**Defining equation (spheroid)**

$$\frac{x^2 + y^2}{1 + v^2} + \frac{z^2}{v^2} = a^2$$

**Solution for  $a \ll \lambda$  (valid for distances to the aperture  $r \ll a$ ):**

$$E_x/E_0 = ikz - \frac{2}{\pi} ikau \left[ 1 + v \arctan v + \frac{1}{3} \frac{1}{u^2 + v^2} + \frac{x^2 - y^2}{3a^2(u^2 + v^2)(1 + v^2)^2} \right]$$

$$E_y/E_0 = -\frac{4ikxyu}{3\pi a(u^2 + v^2)(1 + v^2)^2},$$

$$E_z/E_0 = -\frac{4ikxv}{3\pi(u^2 + v^2)(1 + v^2)},$$

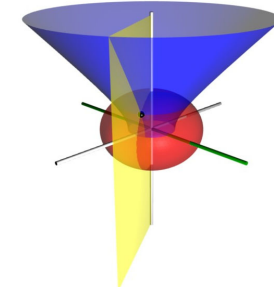
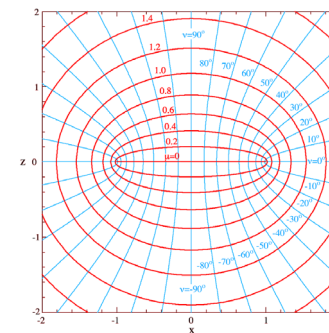
$$H_x/H_0 = -\frac{4xyv}{\pi a^2(u^2 + v^2)(1 + v^2)^2},$$

$$H_y/H_0 = 1 - \frac{2}{\pi} \left[ \arctan v + \frac{v}{u^2 + v^2} + \frac{v(x^2 - y^2)}{\pi a^2(u^2 + v^2)(1 + v^2)^2} \right]$$

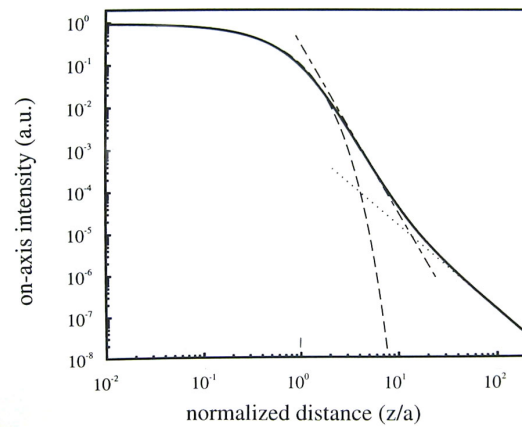
$$H_z/H_0 = -\frac{4ayv}{\pi a^2(u^2 + v^2)(1 + v^2)},$$

## Oblate-spheroidal coordinates

$$\begin{aligned} \text{Coordinate transformation: } x &= a \cosh \mu \cos v \cos \phi & v &= \sinh \mu \\ y &= a \cosh \mu \cos v \sin \phi & u &= \sin v \\ z &= a \sinh \mu \sin v \end{aligned}$$



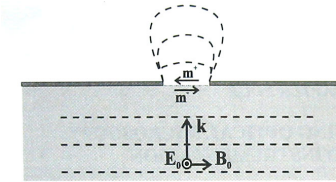
### On-axis intensity behind a circular aperture in an ideal conductor



Nanooptics 15/5

M.H.P.Moers (1995)

### Transmission through Circular Apertures



Near-field Intensity along the symmetry axis

$$I(0,0,z) \propto \left(\frac{4kD}{3\pi}\right)^2 \exp\left(-\frac{3\pi z}{2D}\right) \quad \text{with aperture diameter } D$$

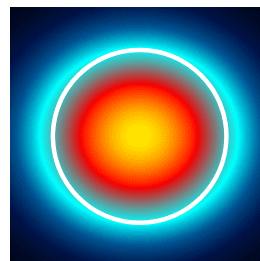
Cross section for radiation to the far-field

$$\sigma = \frac{64}{27\pi} k^4 D^6$$

Nanooptics 15/6

Bouwkamp (1950); M.H.P.Moers (1995)

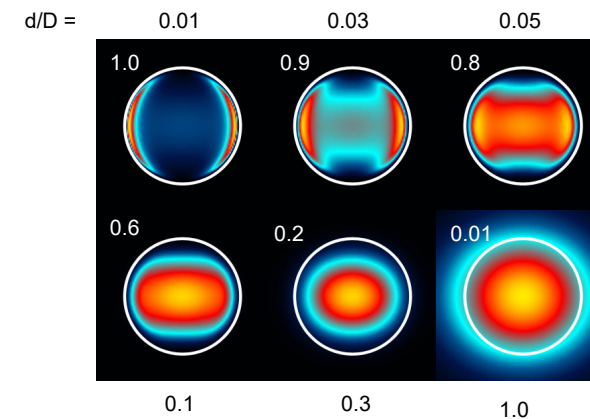
### Field-Map at an Aperture

diameter  $D=50$  nm    distance 50 nm

Nanooptics 15/7

Bouwkamp (1950)

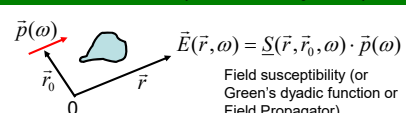
### Field-Map at a Circular Aperture



Nanooptics 15/8

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## Field Susceptibility Method (Green's dyadic)



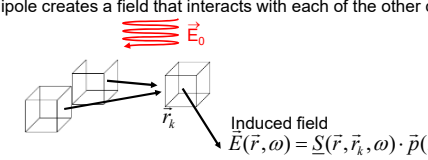
$$\vec{E}(\vec{r}, \omega) = \underline{S}(\vec{r}, \vec{r}_0, \omega) \cdot \vec{p}(\omega)$$

Field susceptibility (or  
Green's dyadic function or  
Field Propagator)

Incident field polarizes the cells  
 $\Rightarrow$  a dipole is induced

Polarization    Polarizability  
 $\vec{p}(\vec{r}_k, \omega) = \chi(\vec{r}_k, \omega) \cdot \vec{E}(\vec{r}_k, \omega)$

Each induced dipole creates a field that interacts with each of the other cells



Induced field  
 $\vec{E}(\vec{r}, \omega) = \underline{S}(\vec{r}, \vec{r}_k, \omega) \cdot \vec{p}(\vec{r}_k, \omega)$

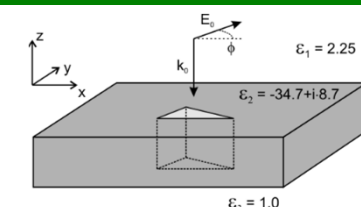
Lippman-Schwinger equation:

$$\vec{E}(\vec{r}, \omega) = \vec{E}_0(\vec{r}, \omega) + \alpha^3 \sum_{\text{all cells}} \underline{S}(\vec{r}, \vec{r}_k, \omega) \cdot \chi \cdot \vec{E}(\vec{r}_k, \omega)$$

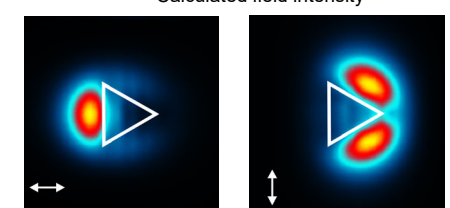
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## Numerical Simulation



Calculated field intensity

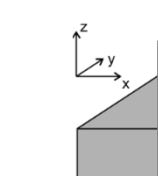
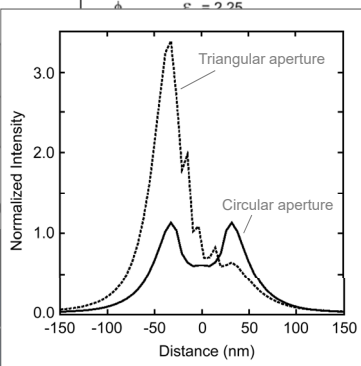
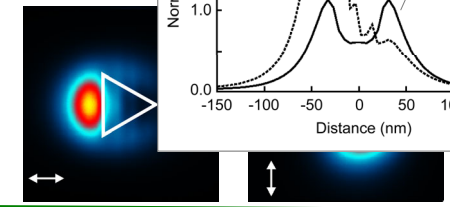


G. Colas des Francs et al. (2005)

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## Numerical Simulation

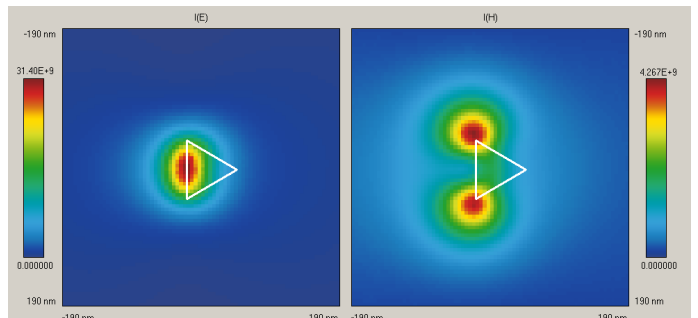




G. Colas des Francs et al. (2005)

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## Numerical Calculations: Electric and Magnetic Fields at a Triangular Aperture



Aperture side length: 80 nm  
Gold thickness : 300 nm  
Distance: 20 nm

Software: COMSOL

T. Ergin

Nanooptics 15/12